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PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Docket No: Q60716

Group Art Unit: 3749

Examiner: Not Yet Assigned

Hiromoto OHNO, et al.

Appln. No.: 10/088,306

Confirmation No.: 2926

Filed: March 18, 2002

For:

CLEANING GAS FOR SEMICONDUCTOR PRODUCTION EQUIPMENT

REQUEST FOR CORRECTED OFFICIAL FILING RECEIPT RECEIVED

Commissioner for Patents Office of Initial Patent Examination Customer Service Center Washington, D.C. 20231

TECHNOLOGY CENTER R3700

Sir:

We enclose a copy of the Official Filing Receipt for the above-identified application and request the following correction(s):

Applicant(s)

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Verification for the requested correction(s) is indicated on the original Declaration and Power of Attorney filed March 18, 2002.

Respectfully submitted,

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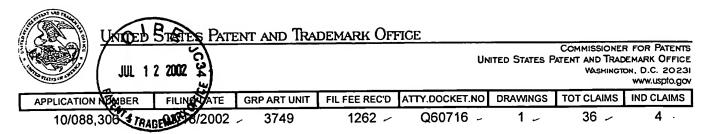
Date: July 12, 2002

Abraham J. Rosner Registration No. 33,276

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CONFIRMATION NO. 2926

FILING RECEIPT

OC000000008249357

23373 SUGHRUE MION, PLLC 2100 PENNSYLVANIA AVENUE, N.W. WASHINGTON, DC 20037

Date Mailed: 06/11/2002

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Applicant(s)

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Domestic Priority data as claimed by applicant

THIS APPLICATION IS A 371 OF PCT/JP01/06164 07/17/2001 * WHICH CLAIMS BENEFIT OF 60/230,811 09/07/2000 * -AND CLAIMS BENEFIT OF 60/261,265 01/16/2001 * (*)Data provided by applicant is not consistent with PTO records.

Foreign Applications

JAPAN 2000-217610 07/18/2000 JAPAN 2000-397269 12/27/2000 JAPAN 2001-189388 06/22/2001

Projected Publication Date: To Be Determined - pending completion of Security Review

Non-Publication Request: No

Early Publication Request: No

Title

Cleaning gas for semiconductor production equipment

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بر در گرد در